

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
Yoshimi SATO et al. :  
Serial No. NEW : **Attn: APPLICATION BRANCH**  
Filed September 22, 2003 : **Attorney Docket No. 2003\_1356**

COATING SOLUTIONS FOR USE IN  
FORMING BISMUTH-BASED  
FERROELECTRIC THIN FILMS AND A  
METHOD OF FORMING BISMUTH-BASED  
FERROELECTRIC THIN FILMS USING  
THE COATING SOLUTIONS  
(Rule 1.53(b) Continuation  
of Serial No. 09/793,490,  
Filed February 27, 2001)

**CLAIM OF PRIORITY UNDER 35 USC 119**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450


Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 50889/2000, filed February 28, 2000, as acknowledged in the Declaration of this application.

A certified copy of said Japanese Patent Application of record in parent application Serial No. 09/793,490, filed February 27, 2001.

Respectfully submitted,

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